



Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No. NOVLP096/NVLS-2902	Application No.: 10/815,560
	Applicant: Wongsenakhum et al. Filing Date March 31, 2004	Group 2823

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
<i>[Signature]</i>	A1	5,956,609	09.1999	Lee et al.	—	—	
	A2	2003/0104126	06.2003	Fang et al.	—	—	

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
<i>[Signature]</i>	C1	Chan et al., "Methods for Growing Low-Resistivity Tungsten Film", Novellus Systems, Inc., filed November 1, 2005, Application No. 11/265,531, pages 1-35. [NOVLP137/NVLS-0003093]
	C2	Levy et al., "Deposition of Tungsten Nitride", Novellus Systems, Inc., filed December 16, 2005, Application No. 11/305,368, pages 1-39. [NOVLP063D1/NVLS-2615D1].
	C3	U.S. Office Action mailed December 28, 2005, from U.S. Application No. 10/649,351 [NOVLP033X1/NVLS-000498X1].
Examiner <i>Michelle Estrada</i>	Date Considered <i>3/3/06</i>	

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



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<i>hge</i>	C1	Wongsenakhum et al., "Reducing Silicon Attack and Improving Resistivity of Tungsten Nitride Film", Novellus Systems, Inc., filed February 6, 2006, Application No. Not yet assigned, pages 1-26. [NOVLP138/NVLS-3094]
Examiner	<i>Rachel Estrada</i>	
	Date Considered	<i>4/13/06</i>

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.